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Advanced Fabrication Technologies for Micro/Nano Optics and Photonics XVI

Georg von Freymann
Eva Blasco
Debashis Chanda
Editors

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Contents

v *Conference Committee*

METASURFACES

12433 02 **Novel fabrication method for highly conformable THz metasurfaces (3D Printing Best Paper Award in OPTO)** [12433-3]

MICROPTICS I

12433 03 **Laser direct writing of interfacing structures for short-distance optical interconnections (Invited Paper)** [12433-6]

12433 04 **Direct laser writing of micrograting arrays using a spatial light modulator** [12433-7]

PHOTONICS

12433 05 **Tailoring optical birefringence of polymers using 3D femtosecond laser structuring (Best Paper Award)** [12433-10]

12433 06 **Temperature compensated strain sensor in fused silica by femtosecond laser inscription** [12433-11]

12433 07 **Creating fiber-embedded photonic circuitry by liquid-phase structuring of multi-material cores (Best Student Paper Award)** [12433-12]

MICROPTICS II

12433 08 **A novel fabrication method for high-precision polymer aspherical lenses (Invited Paper)** [12433-13]

12433 09 **Reprogrammable diffractive micro-optical elements** [12433-15]

12433 0A **A bi-axially accelerating Airy beam for miniaturized light-sheet microscopy** [12433-16]

VOLUMETRIC AND GREYSCALE PRINTING

12433 0B **Sub-100 nm feature sizes realized by cost-effective microscope projection photolithography** [12433-21]

NOVEL MATERIALS AND MULTIMATERIAL PRINTING

12433 0C **Multiphoton polymerization using upconversion nanoparticles for adaptive high-resolution 3D printing** [12433-27]

12433 0D **Multi-material additive manufacturing based on µ-dispenser technology for tailored polymer micro-optics** [12433-28]

12433 0E **All-printed SU8-perovskite DFB laser** [12433-30]

QUALITY CONTROL FOR MICRO/NANO FABRICATION: JOINT SESSION WITH CONFERENCES 12433 AND 12412

12433 0F **Manufacturing acceleration of free-form micro-optical arrays (FMOAs) with CAD algorithms** [12433-32]

POSTER SESSION

12433 0G **Integration of UV-nanoimprint lithography with two-photon polymerization for scalable production** [12433-40]

12433 0H **Investigation of plasma etching for interlayer dielectric planarization in high-efficiency deep-ultraviolet nanowire LEDs** [12433-41]

12433 0I **Large-area scatterometry for nanoscale metrology** [12433-42]

12433 0J **Two-photon 3D-nanostructuring in metal-organic frameworks** [12433-46]

12433 0K **High-efficiency fill factor recovery using refractive microlens arrays imprinted on 0.5-256 kpixel front-side illuminated SPAD imagers** [12433-48]

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